

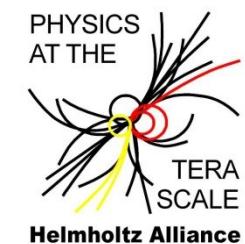
Measurement of the drift velocities of electrons and holes in high-ohmic <100> silicon

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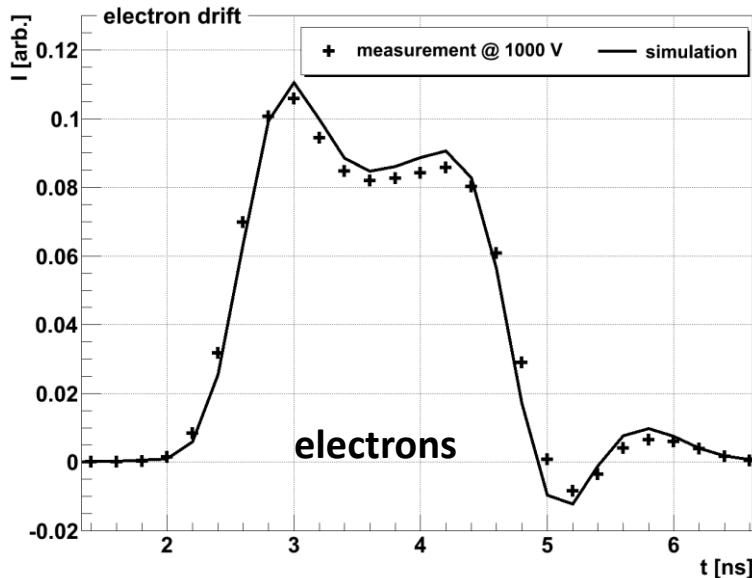
Federal Ministry
of Education
and Research

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Institut für Experimentalphysik
Universität Hamburg

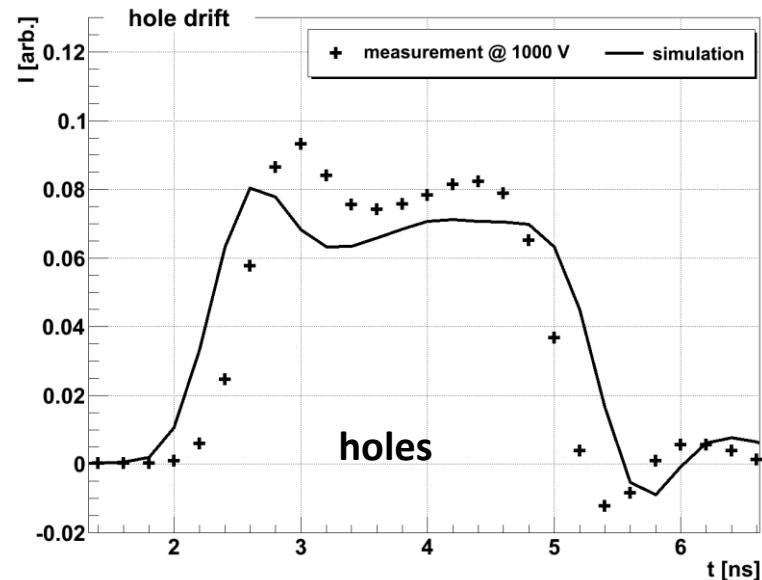


1 – Motivation

Motivation



**200 µm
<100> sensor**
**drift model:
Jacoboni 1977**
 \downarrow
**often used for
<100>**



The <100> drift velocity is a fundamental material parameter!

BUT: The literature mobility models for <100> and <111> direction do not describe measurements of non irradiated sensors

Precise knowledge of the drift velocities of electrons and holes is needed for precise simulations and the analysis of (edge-)TCT

2 – Experimental method

Diodes and measurements

- **Diodes:** High-ohmic <100> float-zone silicon p⁺nn⁺ and n⁺pp⁺ pad diodes

Three different sensors investigated:

| | Vendor | Bulk | w [μm] | U_{dep} [V] | N_{eff} [cm^{-3}] | ρ [$\text{k}\Omega\text{cm}$] |
|----------------------|--------|--------|---------------------|----------------------|---------------------------------------|--------------------------------------|
| Standard sensor → | HPK | N-type | 200±2 | 90 | $2.9 \cdot 10^{12}$ | 1.5 |
| Used for cross check | HPK | P-type | 200±2 | 115 | $3.8 \cdot 10^{12}$ | 1.1 |
| | CiS | N-type | 287±3 | 50 | $0.8 \cdot 10^{12}$ | 5.5 |

Diodes and measurements

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Three different sensors investigated:

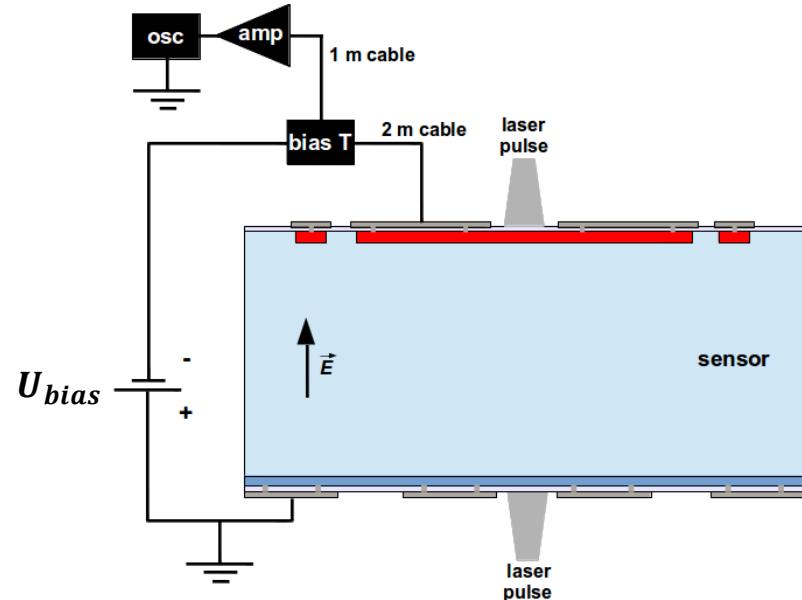
Standard sensor →

Used for cross check

| Vendor | Bulk | w [μm] | U _{dep} [V] | N _{eff} [cm ⁻³] | ρ [kΩcm] |
|--------|--------|--------|----------------------|--------------------------------------|----------|
| HPK | N-type | 200±2 | 90 | 2.9·10 ¹² | 1.5 |
| HPK | P-type | 200±2 | 115 | 3.8·10 ¹² | 1.1 |
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Transient current technique TCT

- Pulsed laser generates e-h pairs in the sensor
- Charge carriers drift in electric field
→ induced signal $I \propto v_d(E(x))$

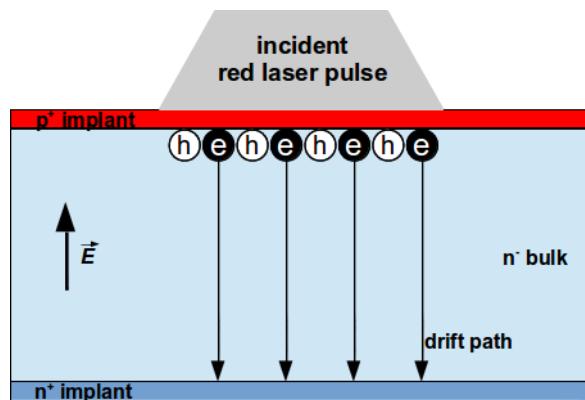


Measurements

- $U_{dep} < U_{bias} \leq 1000$ V steps of $\Delta U_{bias} = 10$ V
- Seven temperatures between 233 K and 333 K

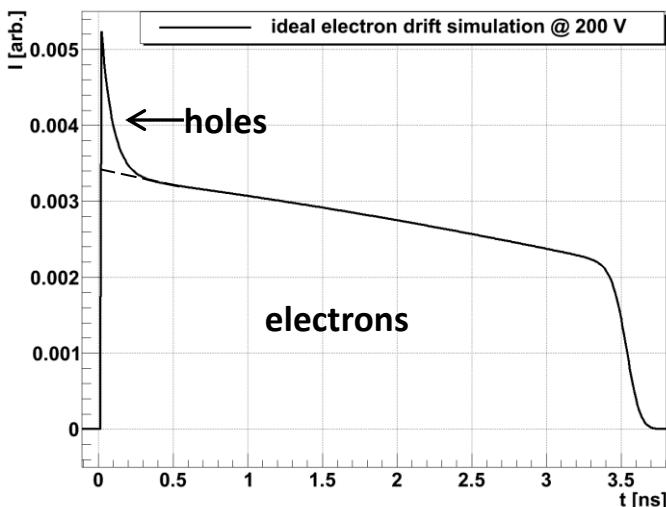
Transient Current Technique

- Red laser $\lambda = 675 \text{ nm}$
 → signal induced by drift of e or h



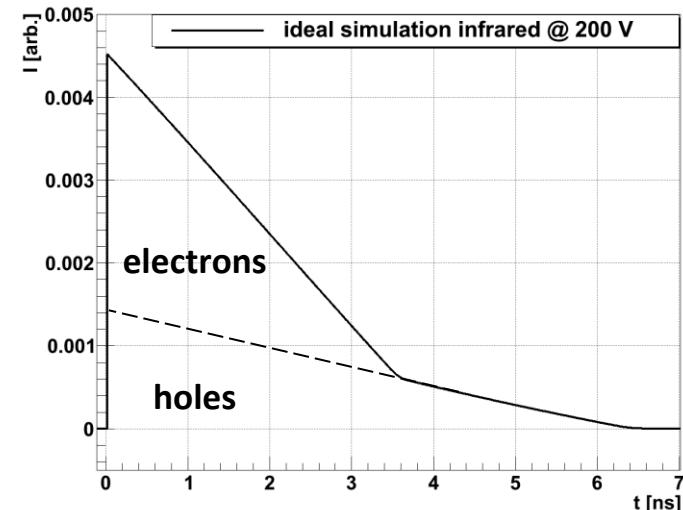
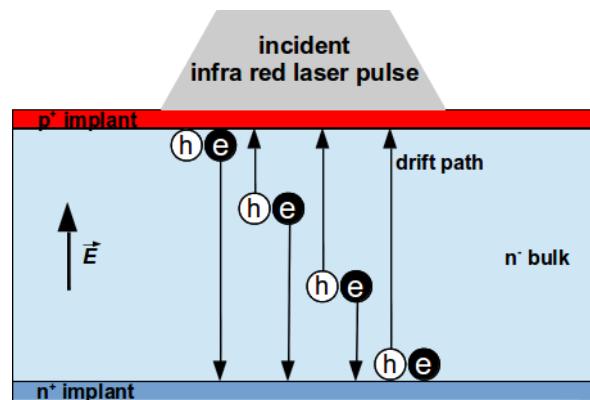
$FWHM \approx 50 \text{ ps}$

initial
charge
distribution



simulation
200 μm sensor
@ 200 V

- Infrared laser $\lambda = 1063 \text{ nm}$
 → simultaneous e and h drift



3 – Analysis methods

Transient current simulation

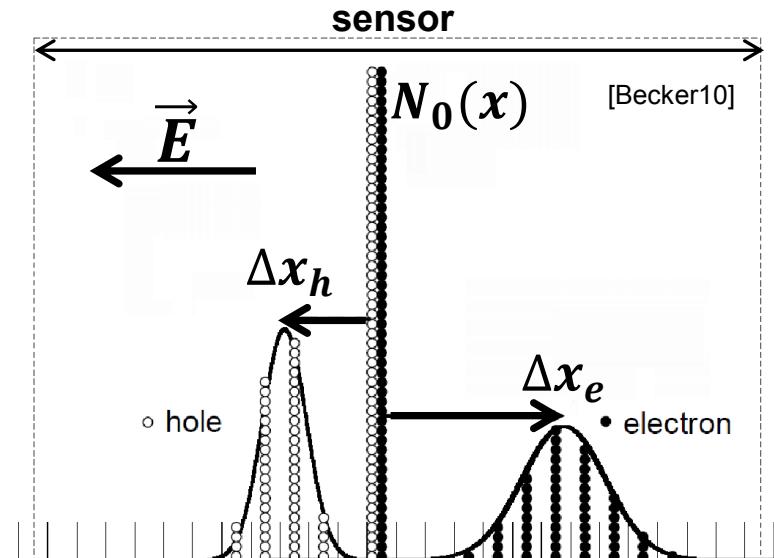
- **Fit of the mobility parameters for red + infrared measurements at all bias voltages + temperatures at once** → up to 622 measurements

- **Grid**

$$\delta x = 100 \text{ nm}$$

- **Charge transport** with $\Delta t = 10 \text{ ps}$
 → **Drift**

$$\Delta x_{e,h} = v_{e,h}(x) \cdot \Delta t = \mu_{e,h}(x) E(x) \cdot \Delta t$$



→ **Diffusion** → Gaussian function

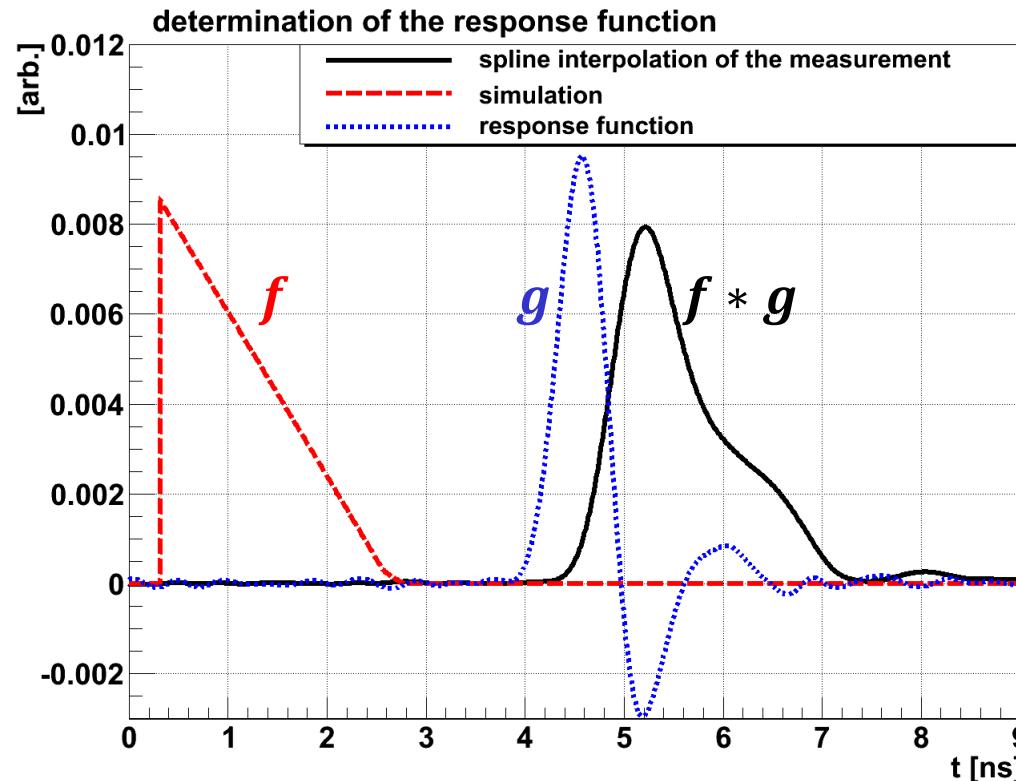
$$\sigma_{e,h}(x) = \sqrt{2D_{e,h}(x) \cdot \Delta t}$$

$$D_{e,h}(x) = \frac{\mu_{e,h}(x) k_b T}{e_0}$$

Transient current simulation: Transfer function

Convolution theorem:

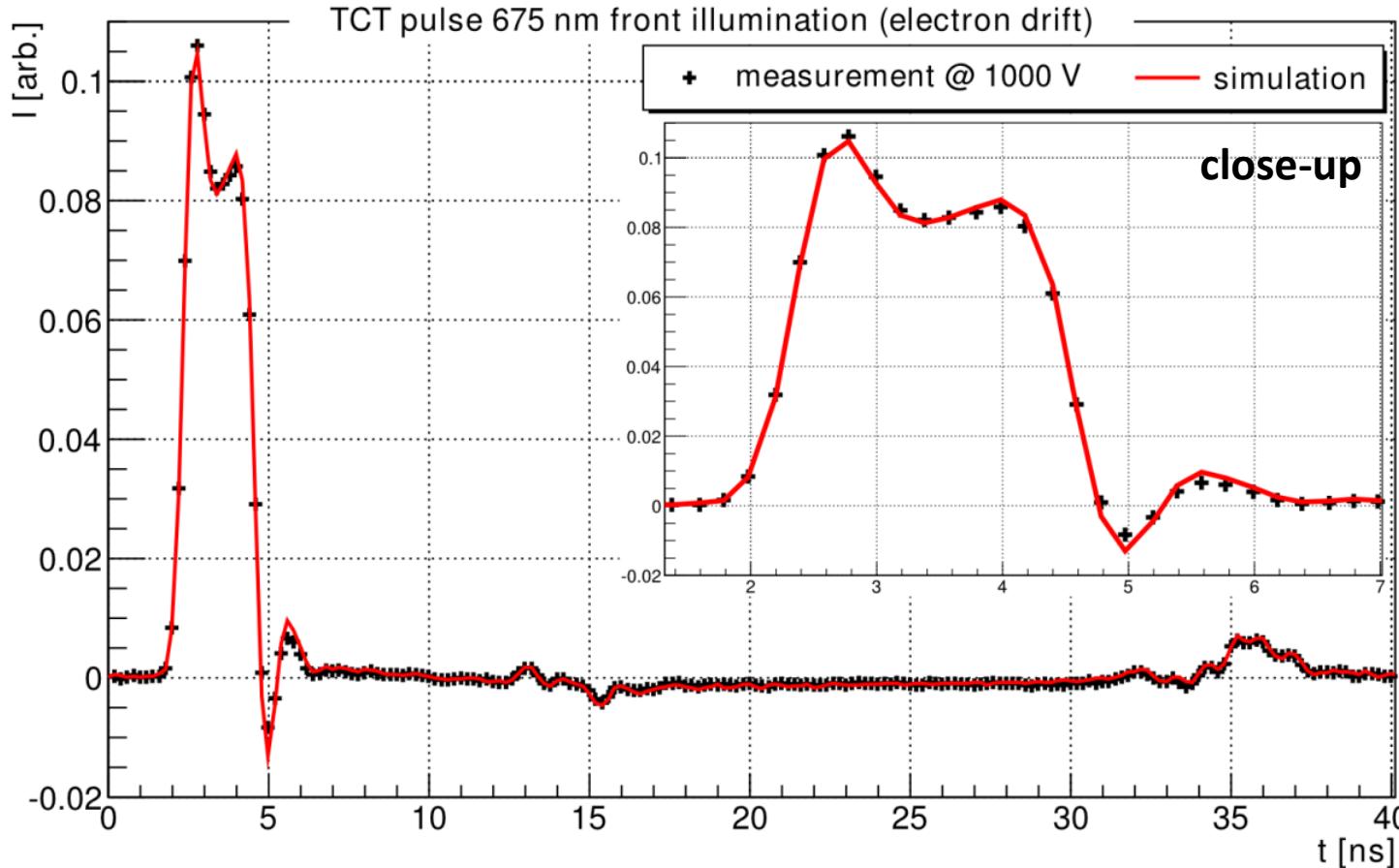
$$\mathcal{F}\{f * g\} = \mathcal{F}\{f\} \cdot \mathcal{F}\{g\}$$



infrared laser
 200 µm sensor
 @ 1000 V and 313 K

Transfer function of
the read-out circuit $\rightarrow g = \mathcal{F}^{-1} \left\{ \frac{\mathcal{F}\{\text{measurement}\}}{\mathcal{F}\{\text{simulation}\}} \right\}$

Transient current simulation: Transfer function



red laser (e drift)
200 μ m sensor
@ 1000 V and 313 K
with g for the
infrared laser

- For all simulations **g for the infrared laser @ 1000 V and 313 K** was used
→ fast signal, e and h contribution

The time-of-flight method

- Carrier **time of flight tof**
→ points of maximum slope
- Signal sampling 200 ps → spline interpolation

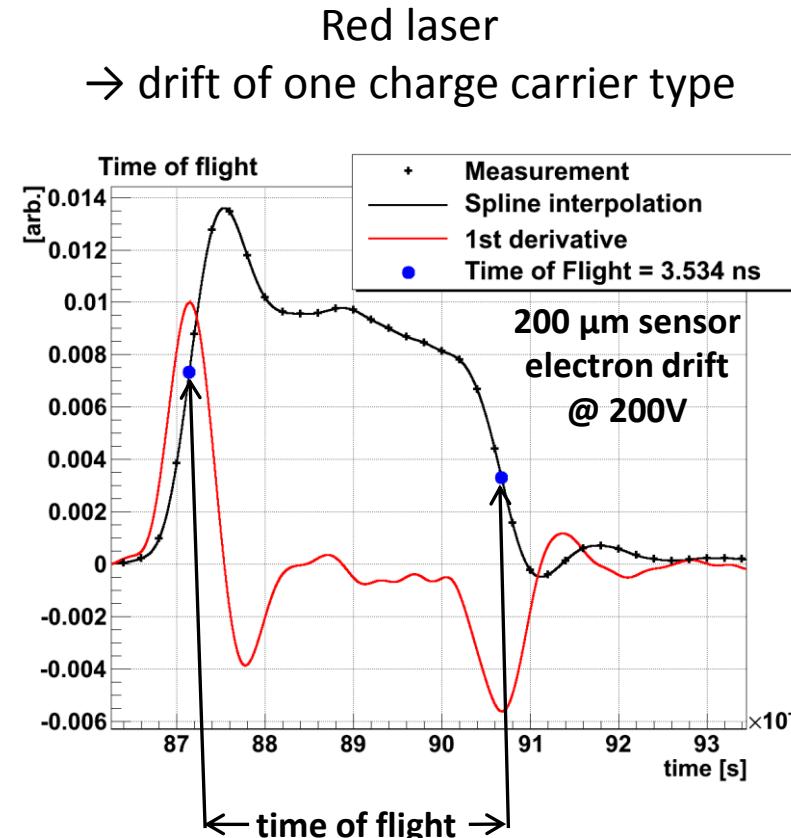
Problem: $E(x) \neq \text{const}$

$$tof = \int_0^w \frac{dx}{v_d(E(x))}$$

$$\rightarrow \text{Assume } \frac{1}{v_d(E(x))} \propto \frac{1}{E(x)} + \text{const}$$

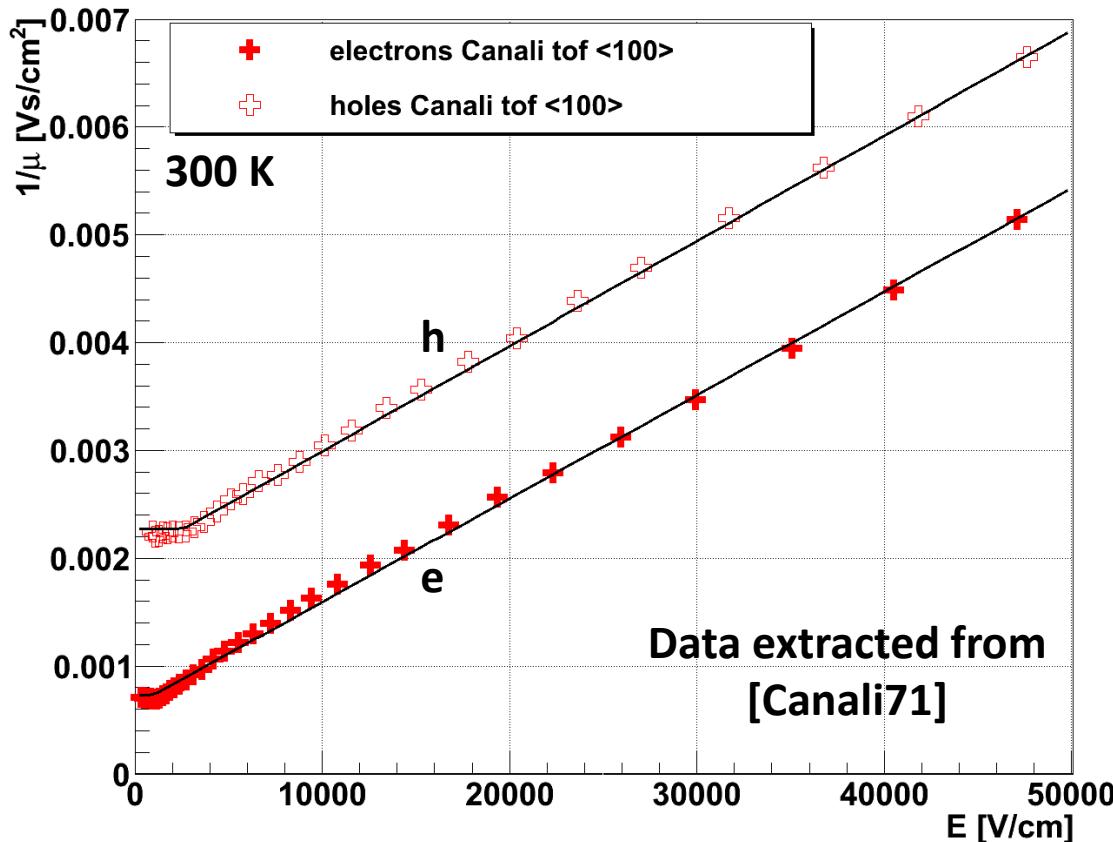
$$\rightarrow tof \propto w \cdot (\langle 1/E(x) \rangle + \text{const})$$

$$\rightarrow v_d \left(\langle 1/E(x) \rangle^{-1} \right) = w/tof$$



4 – Results

Mobility model



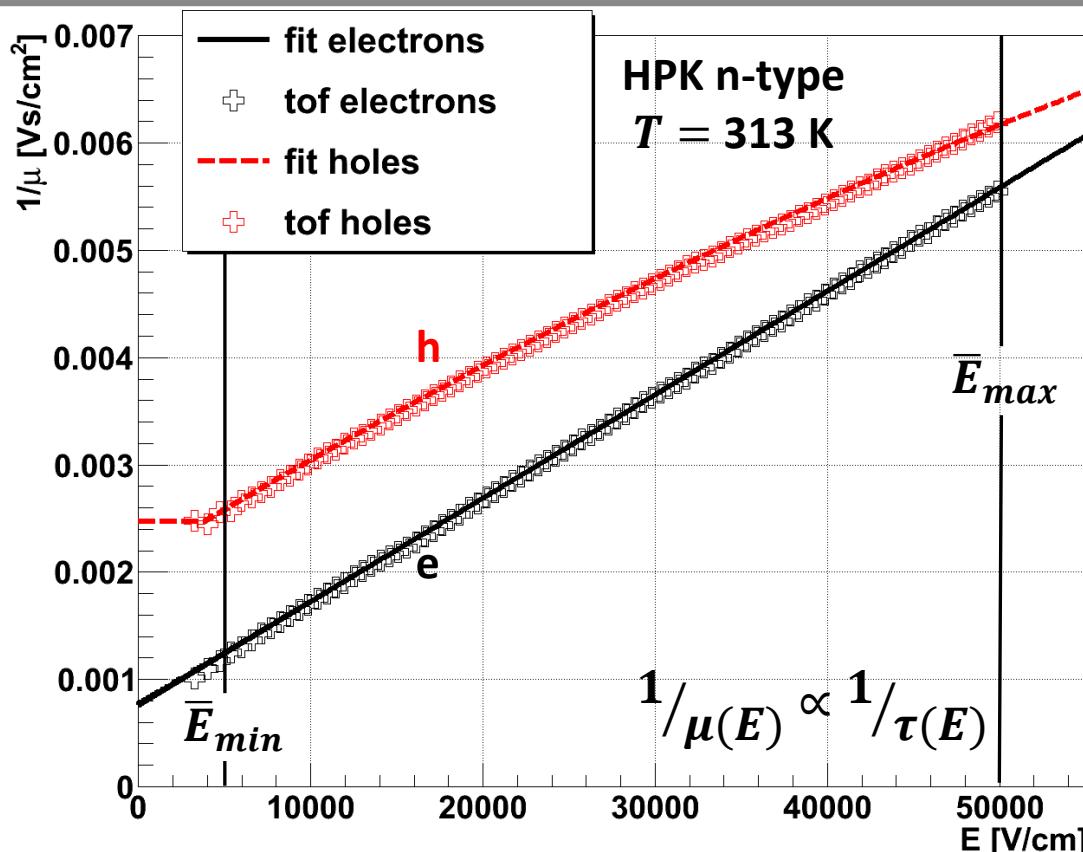
$$v_d(E) = \frac{qE}{2m^*} \tau(E) = \mu(E) \cdot E$$

$$\frac{1}{\mu(E)} \propto \frac{1}{\tau_{coll}} + \frac{1}{\tau_e(E)}$$

 lattice scattering  phonon emission

$$\frac{1}{\mu(E)} = \begin{cases} \frac{1}{\mu_0} & , E < E_0 \\ \frac{1}{\mu_0} + \frac{1}{v_s} \cdot (E - E_0) & , E \geq E_0 \end{cases}$$

Our results



- **Electrons** $\frac{1}{\mu_e(E)} = \frac{1}{\mu_0^e} + \frac{1}{v_s^e} \cdot E$

- **Holes** $\frac{1}{\mu_h(E)} = \max \left(\frac{1}{\mu_0^h}, \frac{1}{\mu_0^h} + b \cdot (E - E_0) + c \cdot (E - E_0)^2 \right)$

T dependence

$$par_i(T) = par_i^{RT} \cdot \left(\frac{T}{300 \text{ K}} \right)^{\alpha_i}$$

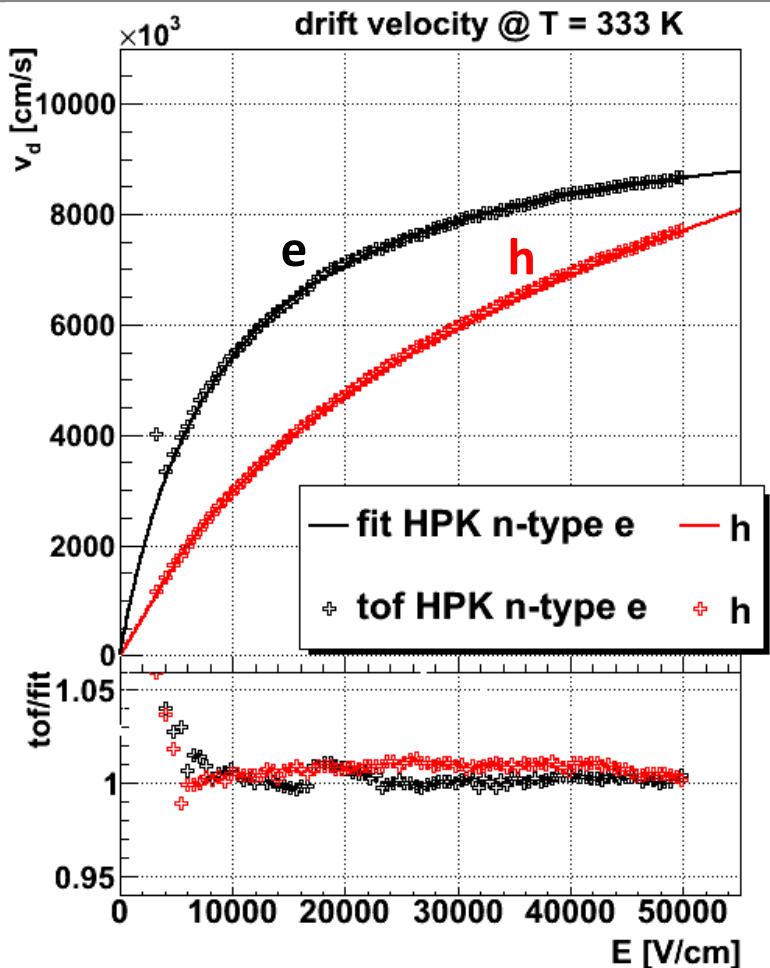
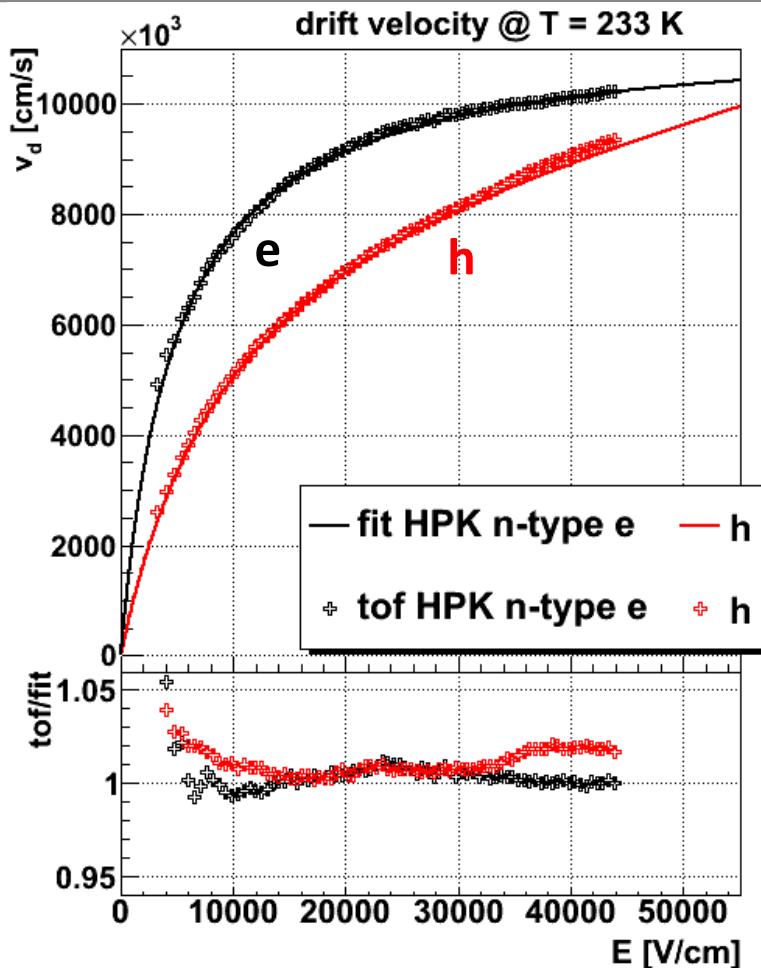
New parameterization fitted for

$$5 \text{ kV/cm} < \bar{E} < 50 \text{ kV/cm}$$

$$233 \text{ K} < T < 333 \text{ K}$$

→ Global fit with $\sigma_{\nu_d} = \pm 2.5 \%$

Global fit results

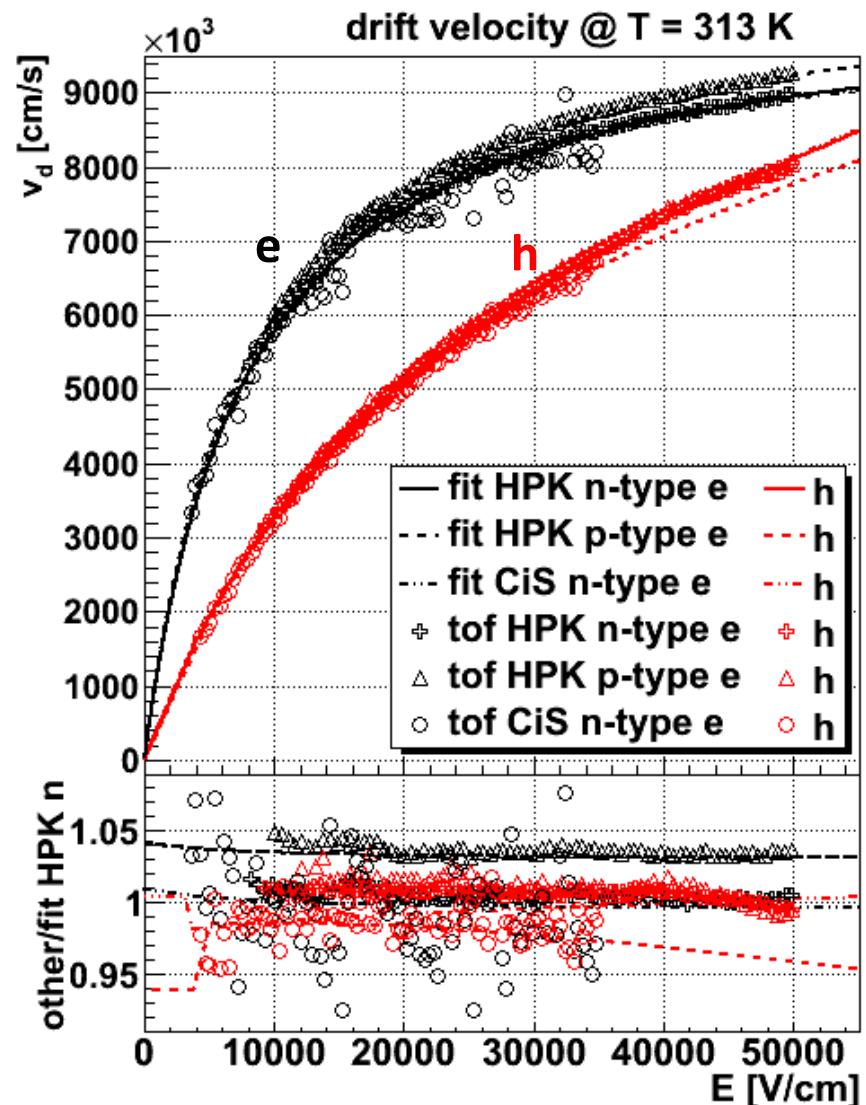


Max tof/fit deviation = 2 % for $E > 7$ kV/cm

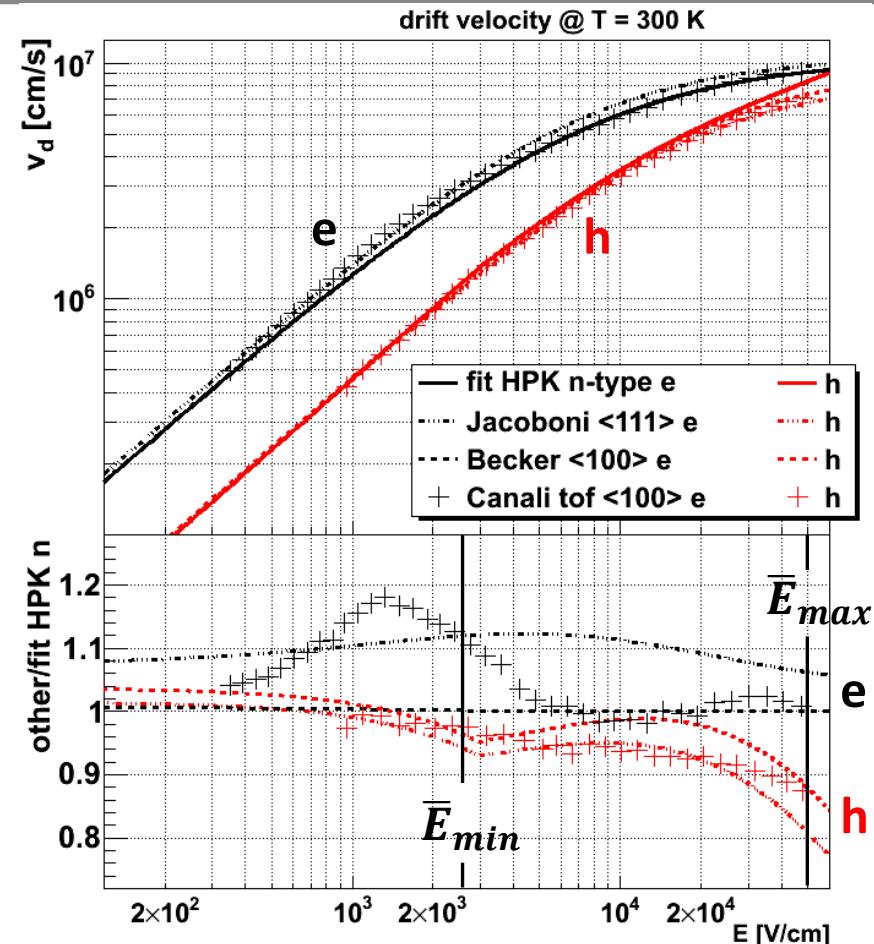
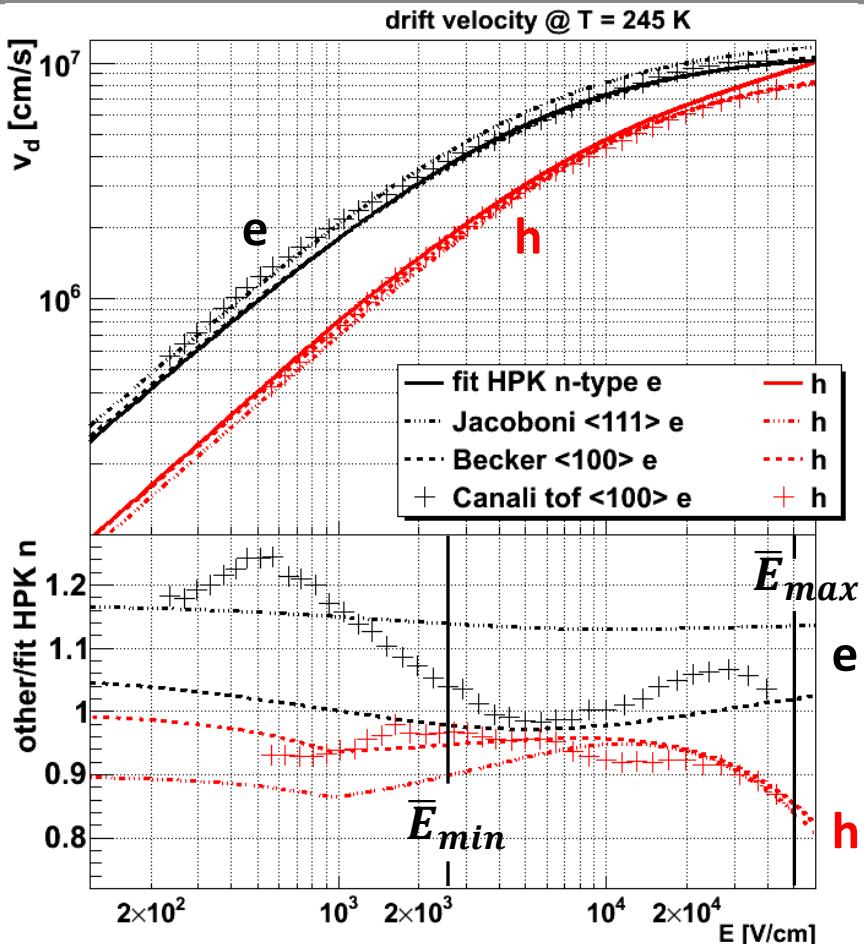
Comparison of different materials

Results of the different sensors @ T=313 K

- The results match within 4 %
- Each point corresponds to one individual measurement!



Comparison with literature



Large differences observed:

$\left\{ \begin{array}{l} \text{Jacoboni } <111>: \text{for e and h} \\ \text{Becker } <100>: \text{only for h @ high fields} \\ \text{Canali } <100>: \text{for h @ high fields and e @ low fields} \end{array} \right.$

5 – Conclusion

Conclusion

- **Analysis**
 - Time-of-flight method ← simple
 - High accuracy despite large field range in the sensor
 - Fit of drift simulation to TCT measurements ← complex
 - Precise determination of electronics response
- **Results**
 - Parametrization of the mobility $\mu(E, T)$ max deviation
 - Results of **different sensors and of fit and tof are consistent** 4 %
 - Results similar to <100> literature values for **electron drift** 5 %
 - Large differences to <100> and <111> literature val. for **hole drift** 15 %
- **Impact**

**The results will improve simulations and the analysis of
TCT and edge-TCT → $E(x)$, $\tau_e(x)$, $\tau_h(x)$**

Thanks for your attention

Special thanks to

J. Becker, J. Erfle, E. Fretwurst , R. Klanner, T. Poehlsen, J. Schwandt

References

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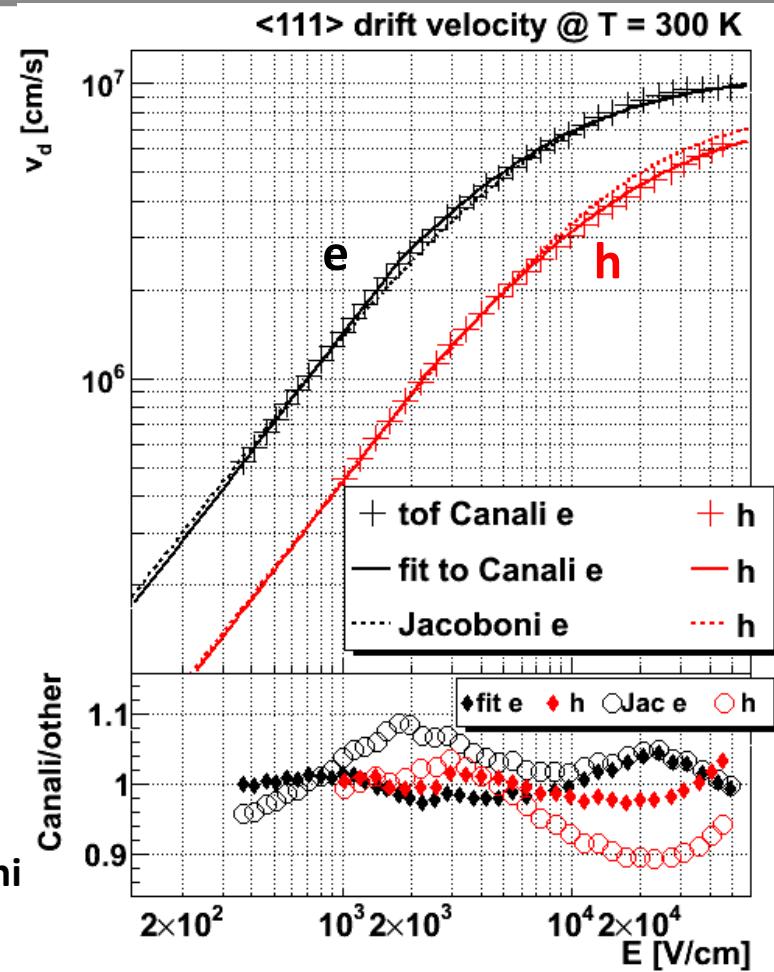
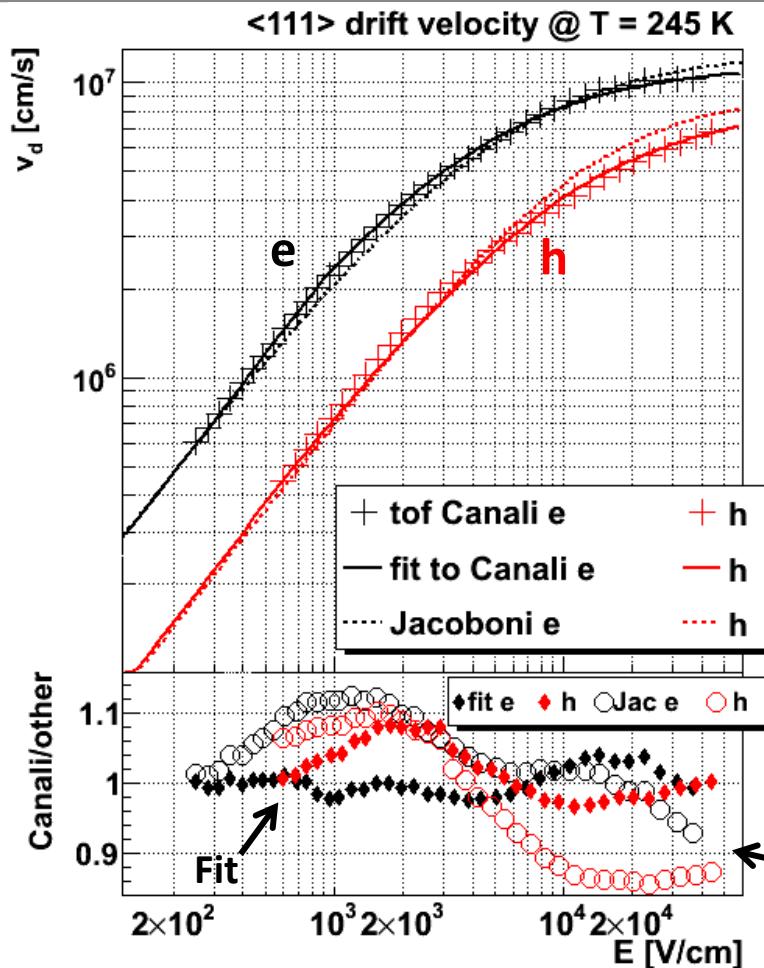
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C Jacoboni, C Canali, G Ottaviani, and A Alberigi Quaranta. A review of some charge transport properties of silicon. *Solid-State Electronics*, 20(2):77-89, 1977.

Backup

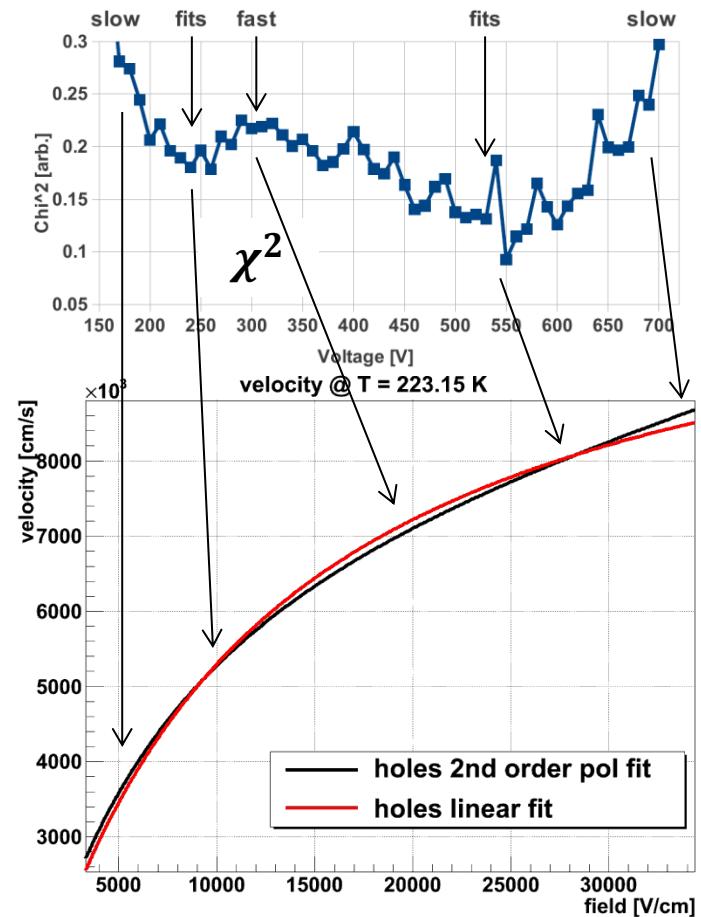
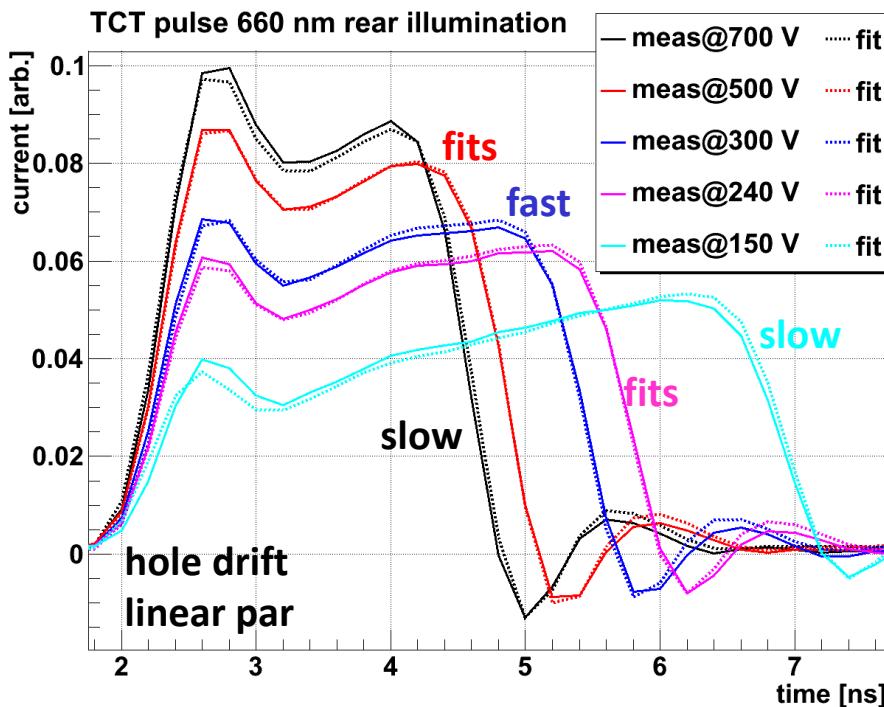
<111> literature mobility



Fit with

$$v_d(E) = E \cdot \mu(E) = E \cdot \min \left(\mu_0, \frac{\mu_0}{1 + \mu_0/v_s \cdot (E - E_0)} \right)$$

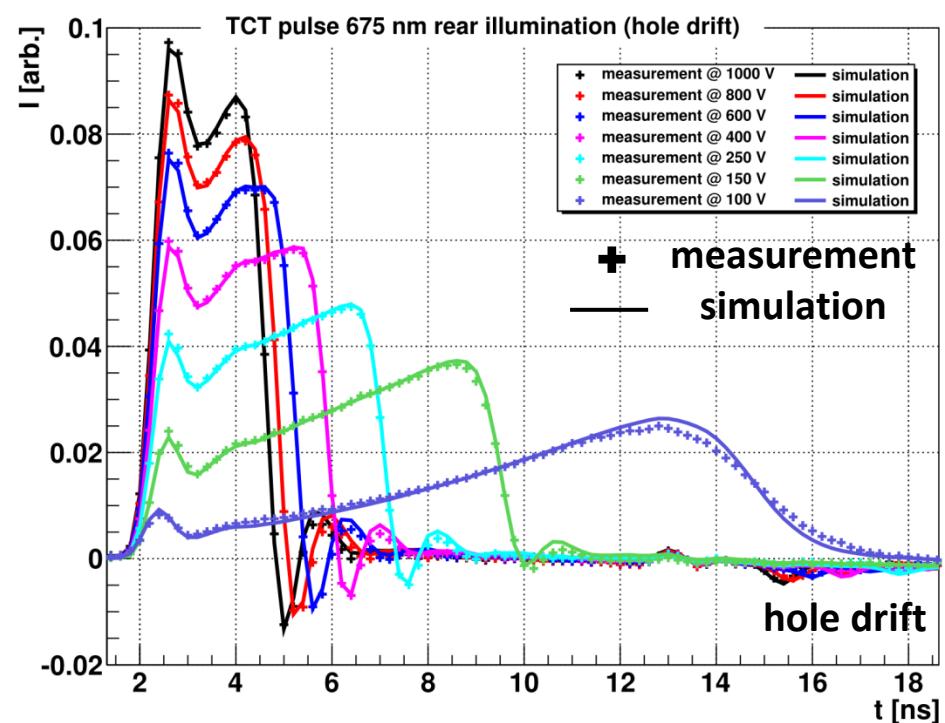
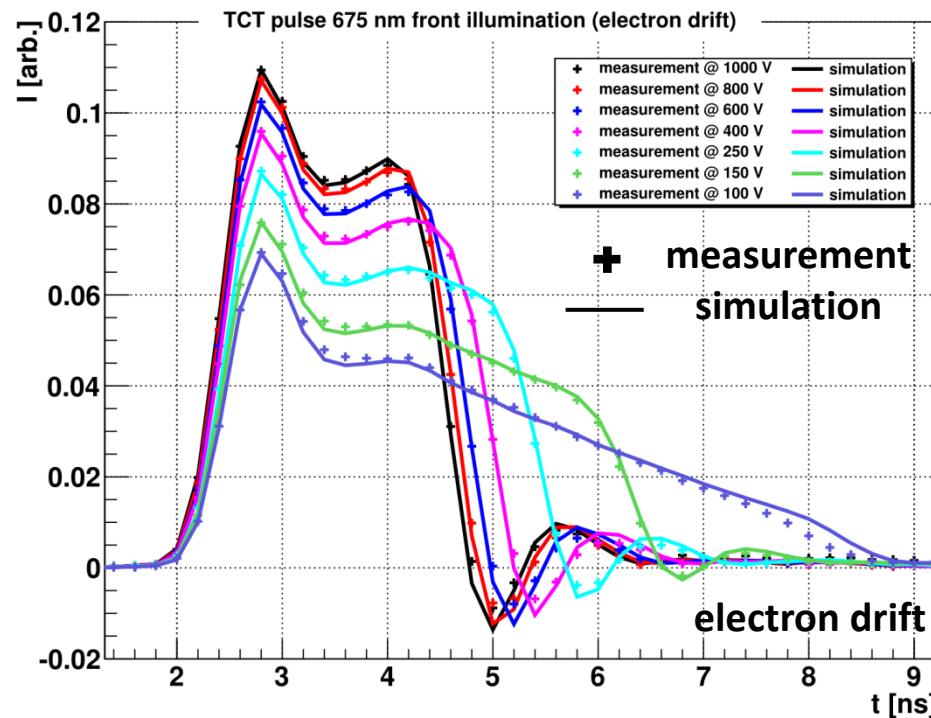
Mobility model: holes linear @ -40C



- Holes
 - Linear par. leads to wrong drift times
 - 2nd degree polynomial

$$\frac{1}{\mu_h(E)} = \max \left(\frac{1}{\mu_0^h}, \frac{1}{\mu_0^h} + b \cdot (E - E_0) + c \cdot (E - E_0)^2 \right)$$

Comparison with measurements

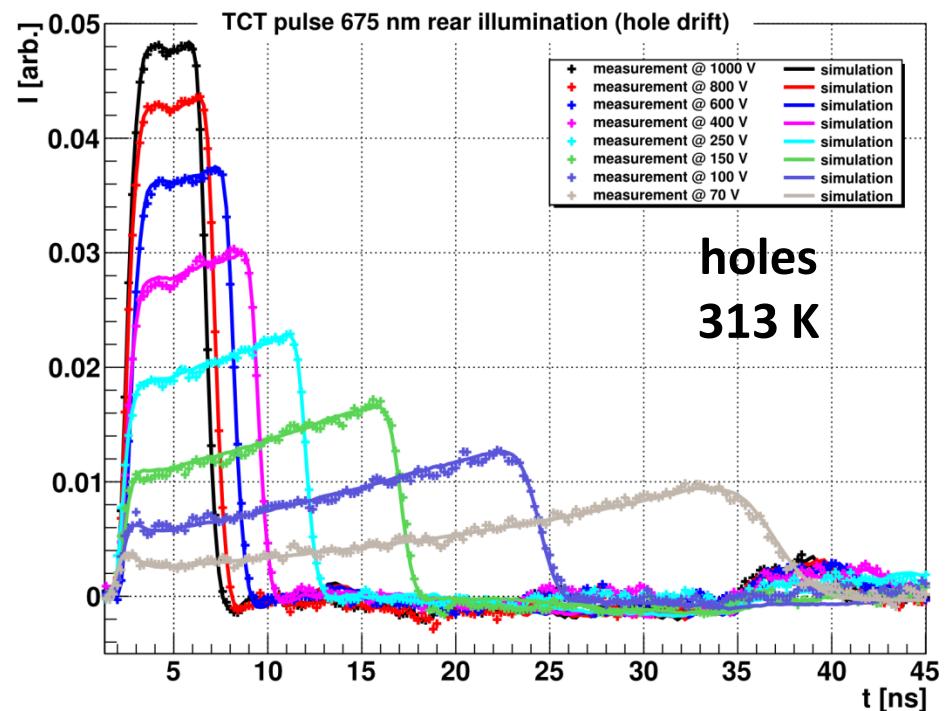
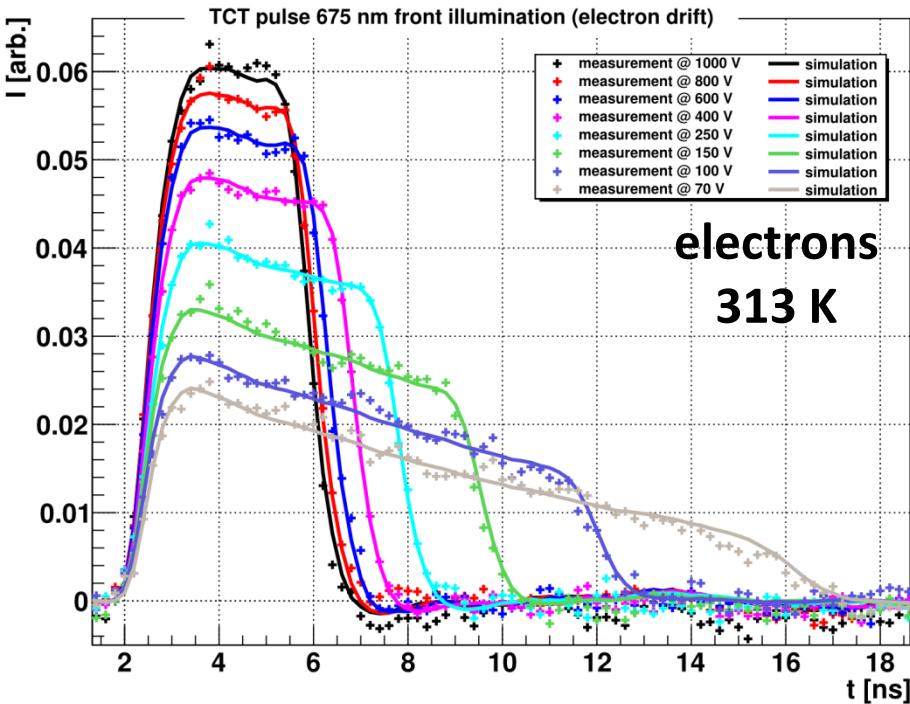


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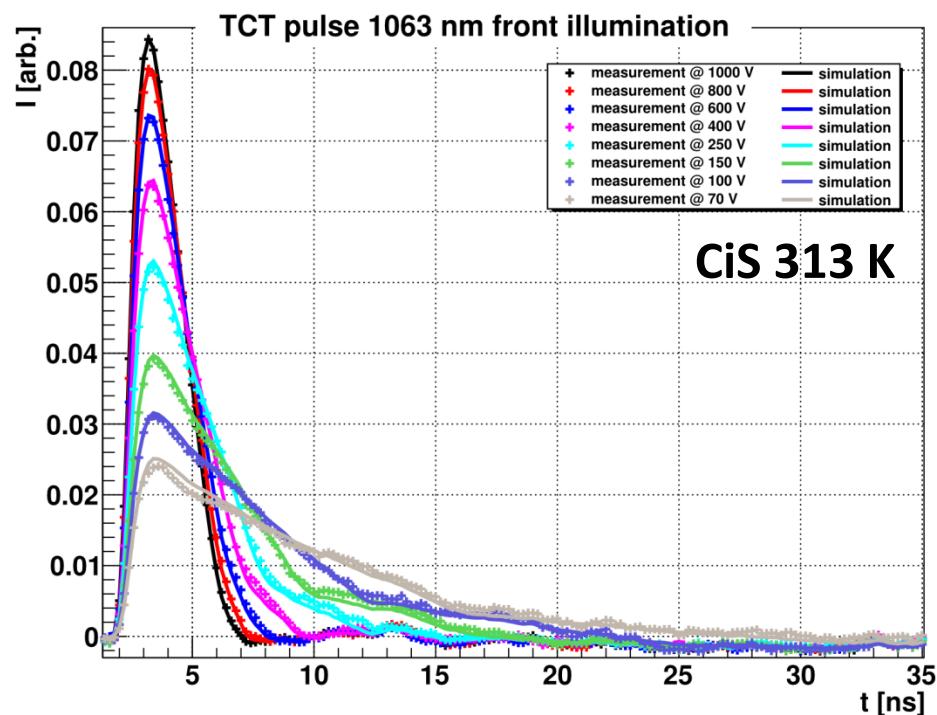
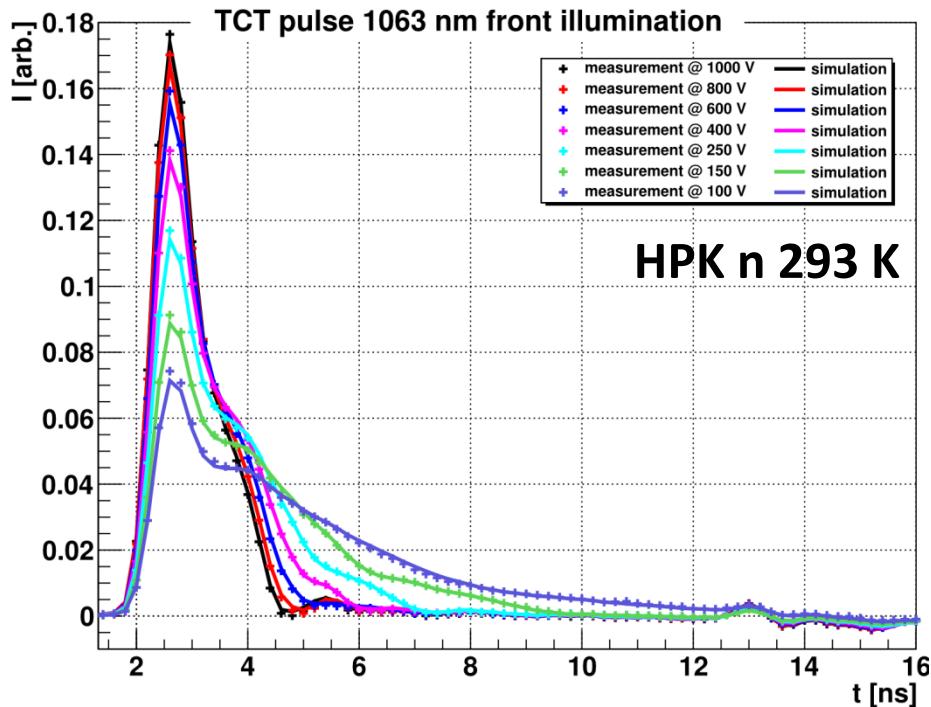
- **Holes** → 2nd degree polynomial

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Backup CiS sensor



Backup infrared

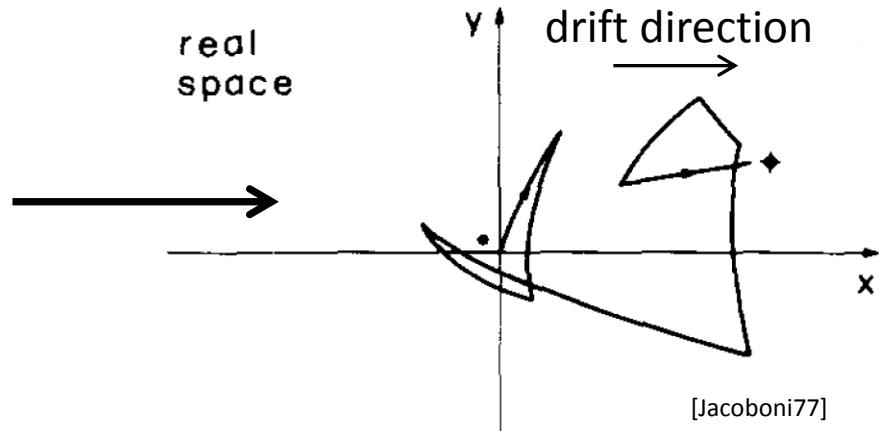


Mobility model

Model based on
[Grove67], [Jacoboni77]

Low electric field $E < E_0$

- Random thermal motion ($v_{th} \approx 10^7$ cm/s) superimposed with drift in electric field

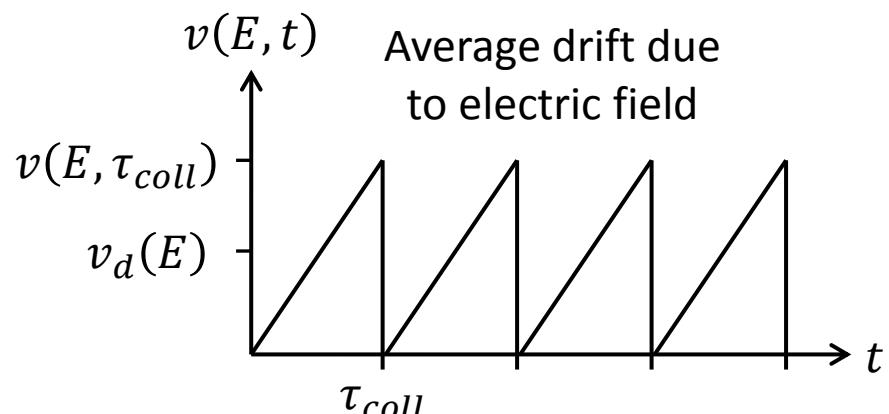


- Mean free time between lattice scattering

$$\tau_{coll} \propto v_{th} \gg v_d(E)$$

- Mean drift velocity

$$v_d(E) = \frac{1}{2} v(E, \tau_{coll}) = \frac{qE}{2m^*} \tau_{coll} = \mu_0 E$$

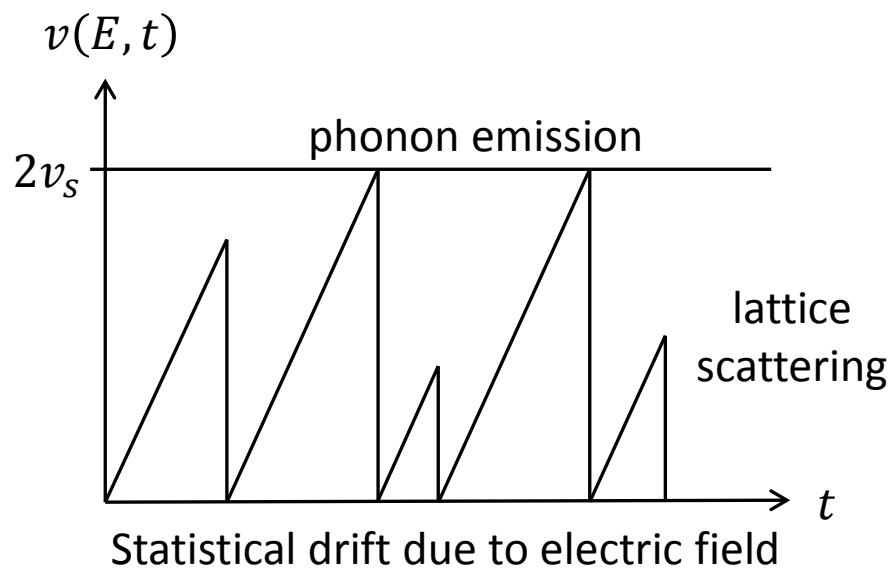


Mobility model

Model based on
[Grove67], [Jacoboni77]

High electric field $E \geq E_0$

- Energy sufficient for optical phonon emission
- Saturation velocity $v_s \propto \sqrt{\hbar\omega_{phonon}}$

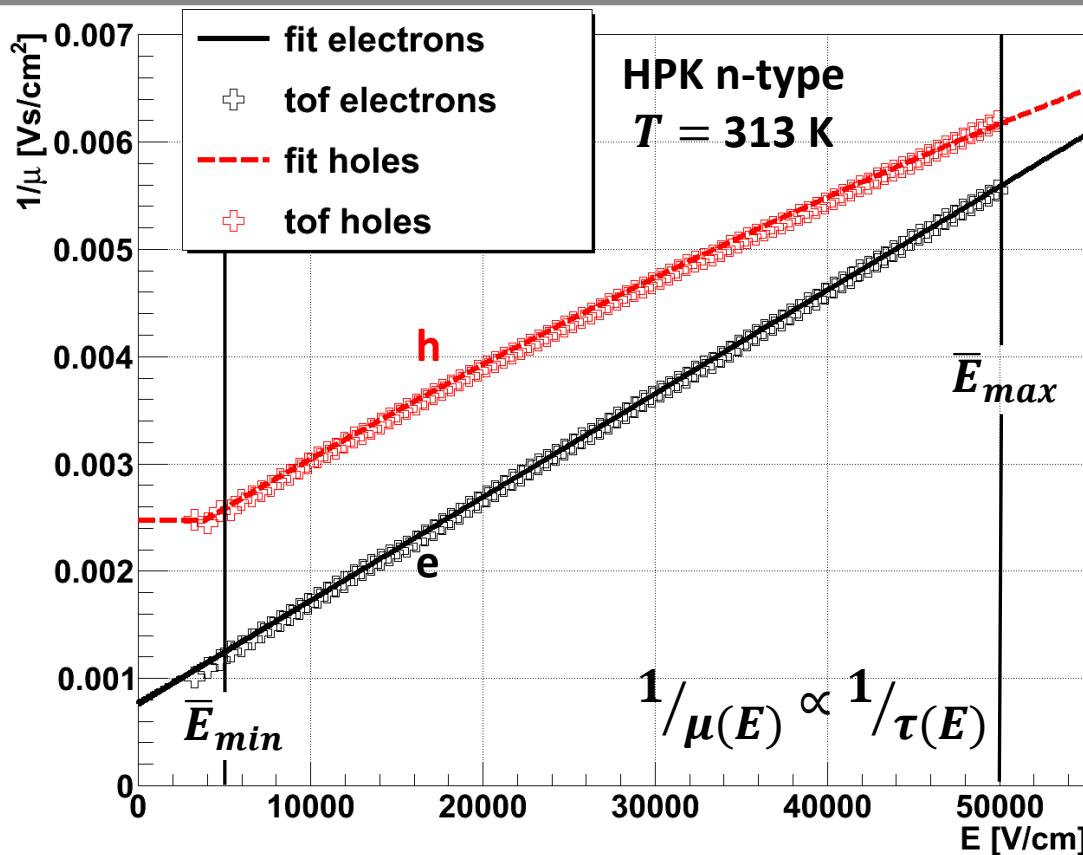


$$v_d(E) = \frac{qE}{2m^*} \tau(E)$$

$$\frac{1}{\tau(E)} = \frac{1}{\tau_{coll}} + \frac{1}{\tau_e(E)}$$

\uparrow \uparrow
 lattice scattering phonon emission

Our results



- **Electrons** $\frac{1}{\mu_e(E)} = \frac{1}{\mu_0^e} + \frac{1}{v_s^e} \cdot E$

- **Holes** $\frac{1}{\mu_h(E)} = \max \left(\frac{1}{\mu_0^h}, \frac{1}{\mu_0^h} + b \cdot (E - E_0) + c \cdot (E - E_0)^2 \right)$

T dependence

$$par_i(T) = par_i^{RT} \cdot \left(\frac{T}{300 \text{ K}} \right)^{\alpha_i}$$

Global fit results ($\sigma_{\nu_d} = \pm 2.5 \%$)

| | | par_i^{RT} | α_i |
|-----------|-----------|---------------------------|------------|
| Electrons | μ_0^e | 1430 cm ² /Vs | -1.99 |
| | v_s^e | $1.05 \cdot 10^7$ cm/s | -0.302 |
| Holes | μ_0^h | 457 cm ² /Vs | -2.80 |
| | b | $9.57 \cdot 10^{-8}$ s/cm | -0.155 |
| | c | $3.24 \cdot 10^{-13}$ s/V | — |
| | E_0 | 2970 V/cm | 5.63 |